

WHAT IS CLAIMED IS:

1. A composition for forming a piezoelectric
containing a dispersoid obtained from metallic compound,
wherein the content of hafnium contained in the
5 composition is 3,000 ppm or less.

2. A composition for forming a piezoelectric
according to claim 1, wherein said metallic compound is
at least one of metallic compound selected from the
10 group consisting of organometallic alkoxides,
organometallic complexes, metal organic salts and metal
hydroxides.

3. A composition for forming a piezoelectric
15 according to claim 1, wherein the content of hafnium
contained in said composition is 2,000 ppm or less.

4. A method for producing a piezoelectric film
comprising the steps of:
20 coating a substrate with a composition for
forming a piezoelectric containing a dispersoid
obtained from metallic compound, in which the content
of hafnium is 3,000 ppm or less, to form a coating
film;
25 drying the coating film; and
sintering the dried coating film to obtain a
piezoelectric film.

5. A piezoelectric element comprising a piezoelectric film held between a lower electrode and an upper electrode, wherein the piezoelectric film is produced by the method of claim 4.

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6. A piezoelectric element according to claim 5, wherein the content of hafnium contained in said piezoelectric film is 3,000 ppm or less.

10 7. An ink jet recording head comprising a pressure chamber communicating with an ink discharge port, a diaphragm provided in correspondence with the pressure chamber, and the piezoelectric element of claim 5 provided in correspondence with the diaphragm,
15 wherein an ink in the pressure chamber is discharged through said ink discharge port by a change of volume in said pressure chamber caused by the piezoelectric element.